

Supporting information

for

Plasma Processes and Polymers

Proceedings of PSE 2006

Manuscript number: 2325

Referring to oral presentation: Session 4 - or0401

"Low-creep metallic thin films and reflective coatings for optical microsystems"

Jan U. Schmidt*; Jens Knobbe, Andreas Gehner

Fraunhofer Institute für Photonische Mikrosysteme,

Maria-Reiche-Straße 2, 01109 Dresden, Germany

Tel.: 0049-351-8823-119; Fax: 0049-351-8823-266;

Email: Jan-Uwe.Schmidt@ipms.fraunhofer.de

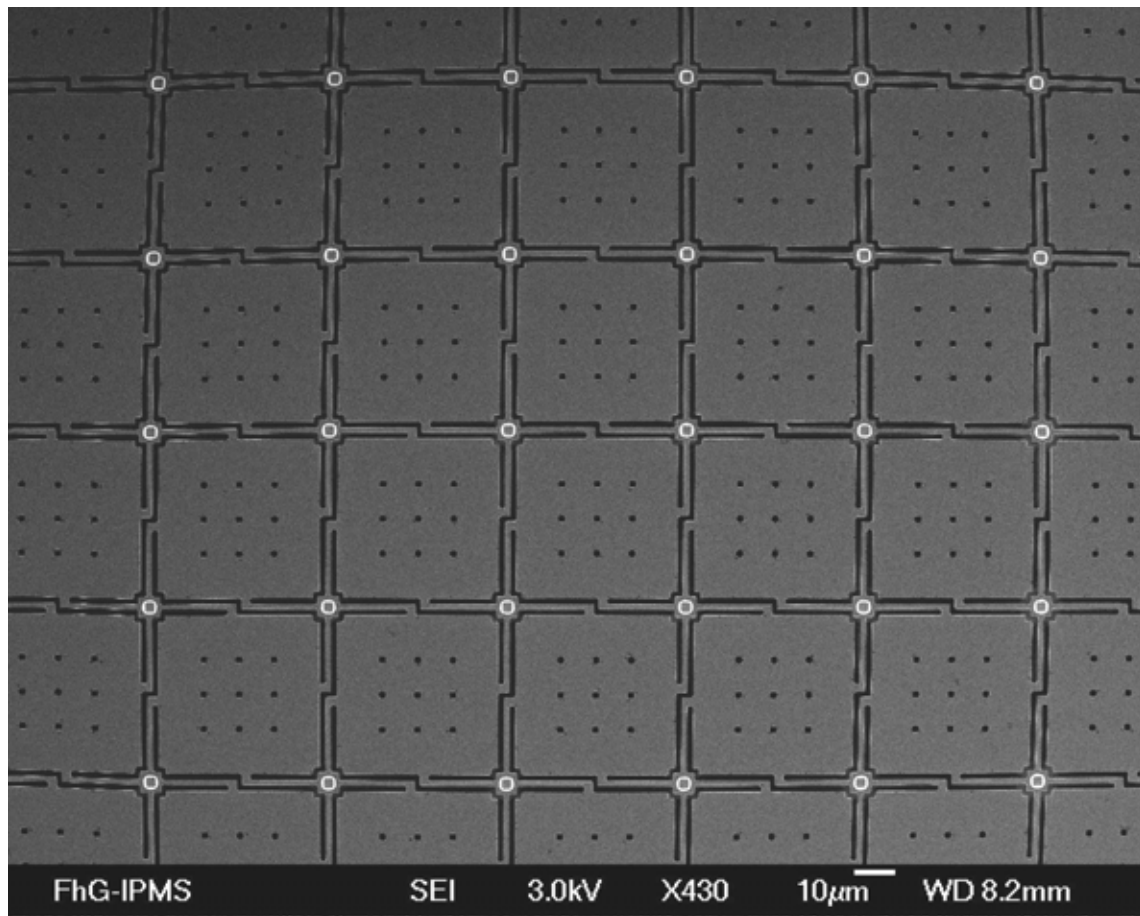


Fig. 5: SEM image of spatial light modulator array with 120 x 120 Al-TiAl-Al piston micromirrors prepared using sputter deposition at room temperature.

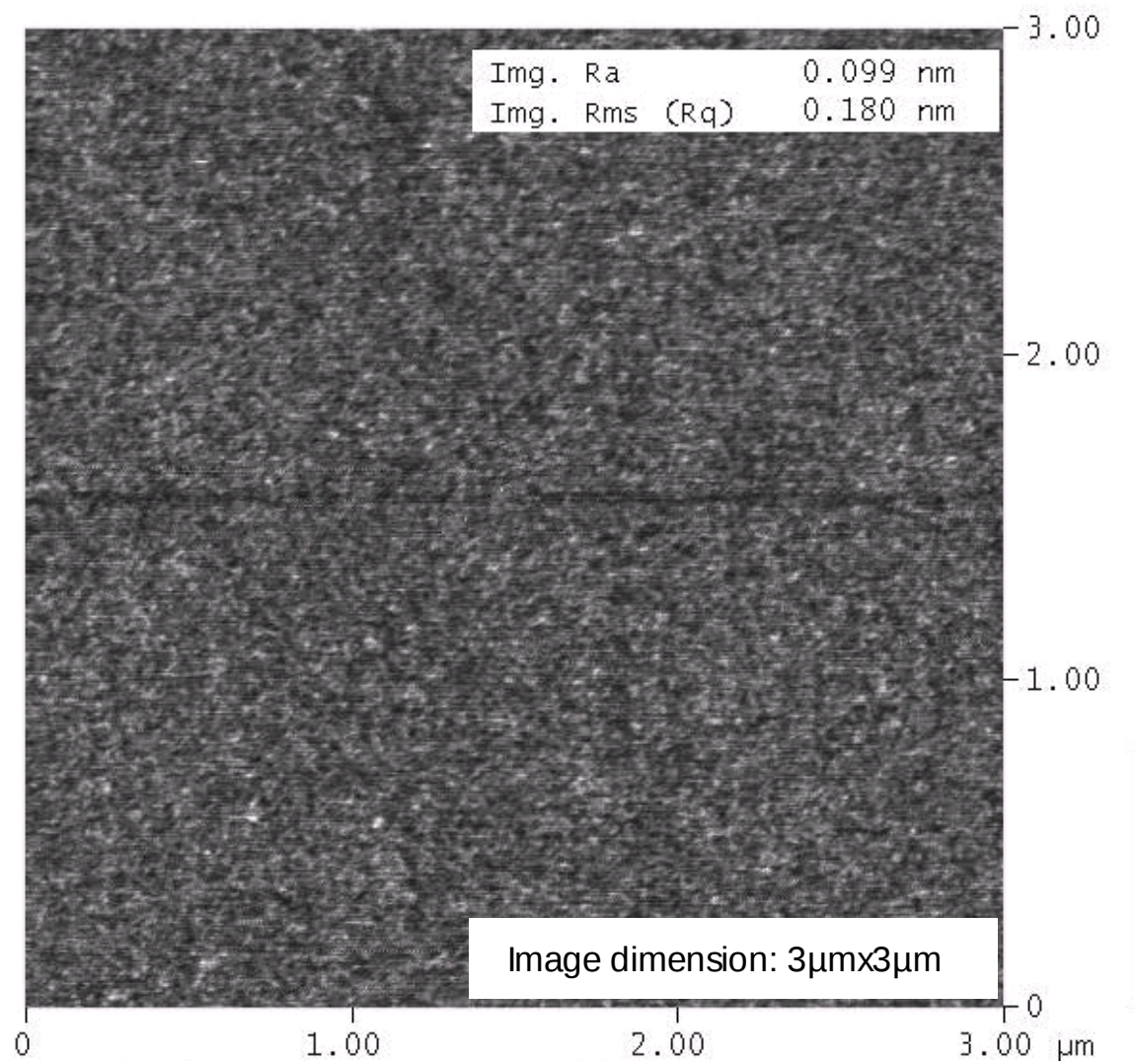


Fig. 6: AFM image of 250nm thick TiAl film on silicon substrate. The rms-roughness of the featureless smooth amorphous film is about 0.2nm.